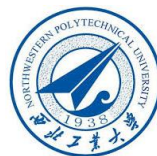




环形正负电子对撞机  
Circular Electron Positron Collider



中国科学院高能物理研究所  
Institute of High Energy Physics  
Chinese Academy of Sciences



# Development of monolithic pixel sensor prototypes for the CEPC vertex detector

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On behalf of the CEPC Vertex detector study team  
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STCF Workshop, Lanzhou, 2024/07/08

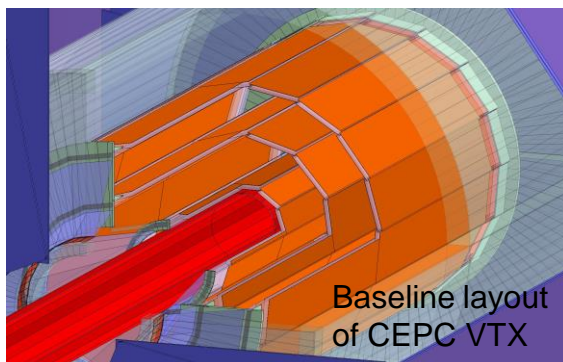
# CEPC Vertex detector requirements

The Circular Electron Positron Collider (CEPC) is a large international scientific facility proposed by the Chinese particle physics community in 2012.

- Efficient tagging of heavy quarks (b/c) and  $\tau$  leptons

→ Excellent impact parameter resolution,

$$\sigma_{r\phi} = 5 \oplus \frac{10}{(p \cdot \sin^{3/2}\theta)} (\mu\text{m})$$



Baseline design parameters for CEPC VTX

	$R$ (mm)	$ z $ (mm)	$ \cos\theta $	$\sigma$ ( $\mu\text{m}$ )
Layer 1	16	62.5	0.97	2.8
Layer 2	18	62.5	0.96	6
Layer 3	37	125.0	0.96	4
Layer 4	39	125.0	0.95	4
Layer 5	58	125.0	0.91	4
Layer 6	60	125.0	0.90	4

## Physics driven requirements

$\sigma_{s.p.}$  **2.8  $\mu\text{m}$**

Material budget **0.15%  $X_0$ /layer**

$r$  of Inner most layer **16 mm**

## Running constraints

Air cooling

beam-related background

radiation damage

## Sensor specifications

Small pixel **~16  $\mu\text{m}$**

Thinning to **50  $\mu\text{m}$**

low power **50 mW/cm<sup>2</sup>**

fast readout **~1  $\mu\text{s}$**

radiation tolerance

**$\leq 3.4$  Mrad/year**

**$\leq 6.2 \times 10^{12} n_{eq}/(\text{cm}^2 \text{ year})$**

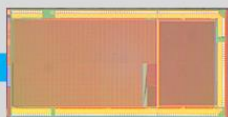
Ref: CEPC Conceptual Design Report, Volume II - Physics & Detector

# Overview of pixel sensors in China for CEPC VTX

## Development of pixel sensors for CEPC VTX supported by

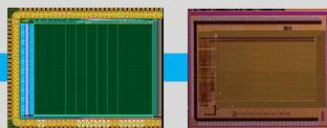
- Ministry of Science and Technology of China (MOST)
- National Natural Science Foundation of China (NSFC)
- IHEP fund for innovation

2015



JadePix-1

2017



JadePix-2/MIC4

2019

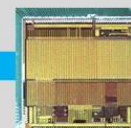


JadePix-3

2020

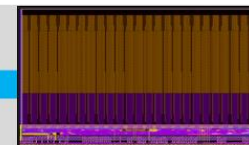


TaichuPix-1

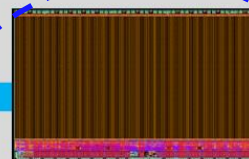


TaichuPix-2

2021



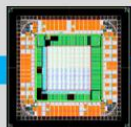
JadePix-4/MIC5



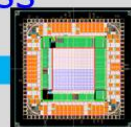
TaichuPix full scale

180nm CIS process

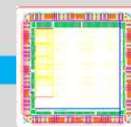
200nm SOI process



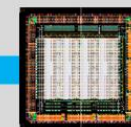
CPV-1



CPV-2



CPV-3



CPV-4

This talk

Ref: "Status report on MAPS in China", 2021 CEPC workshop, Yunpeng Lu

# Main specifications of the full-scale chip

## ■ Bunch spacing

- Higgs: 680 ns; W: 210 ns; Z: **25 ns**
- Max. bunch rate: 40 M/s

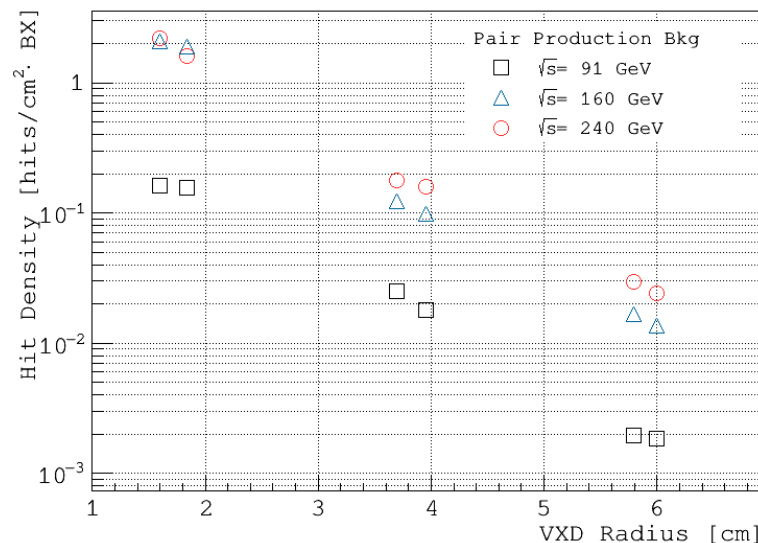
## ■ Hit density

- 2.5 hits/bunch/cm<sup>2</sup> for Higgs/W; 0.2 hits/bunch/cm<sup>2</sup> for Z

## ■ Cluster size: ~3 pixels/hit

- Epi-layer thickness: ~18 μm
- Pixel size: 25 μm × 25 μm

Hit Density vs. VXD Radius

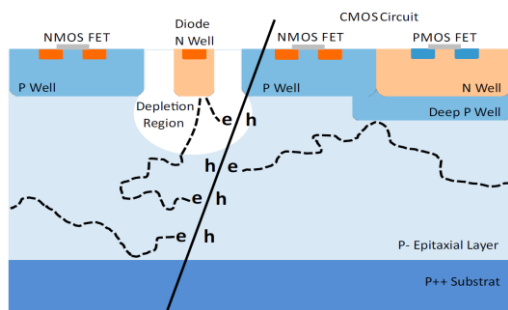


Ref: CEPC Conceptual Design Report, Volume II

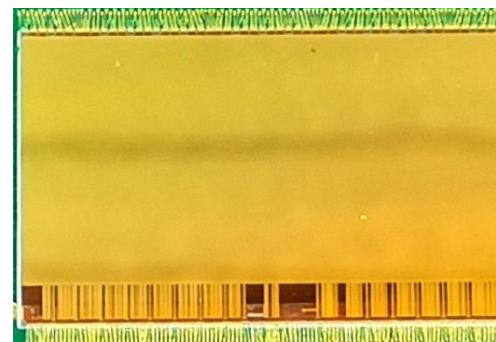
For Vertex	Specs	For High rate Vertex	Specs.	For Ladder Prototype	Specs.
Pixel pitch	≤ 25 μm	Hit rate	120 MHz/chip	Pixel array	512 row × 1024 col
TID	>1 Mrad	Data rate	<b>3.84 Gbps</b> --triggerless <b>~110 Mbps</b> --trigger	Power Density	< 200 mW/cm <sup>2</sup> (air cooling)
		Dead time	< 500 ns --for 98% efficiency	Chip size	~1.4 × 2.56 cm <sup>2</sup>

# TaichuPix prototypes overview

- **Motivation: a large-size & full functionality pixel sensor for the first 6-layer vertex detector prototype**
- **Major challenges for design**
  - Small pixel size → high resolution (3-5  $\mu\text{m}$ )
  - High readout speed (dead time < 500 ns @ 40 MHz) → for CEPC Z pole
  - Radiation tolerance (per year): 1 Mrad TID
- **Completed 3 rounds of sensor prototyping in a 180 nm CMOS process**
  - Two MPW chips (5 mm × 5 mm)
    - TaichuPix-1: 2019; TaichuPix-2: 2020 → feasibility and functionality verification
  - 1<sup>st</sup> engineering run
    - Full-scale chip: TaichuPix-3, received in July 2022 & March 2023



**CMOS  
monolithic  
pixel sensor**

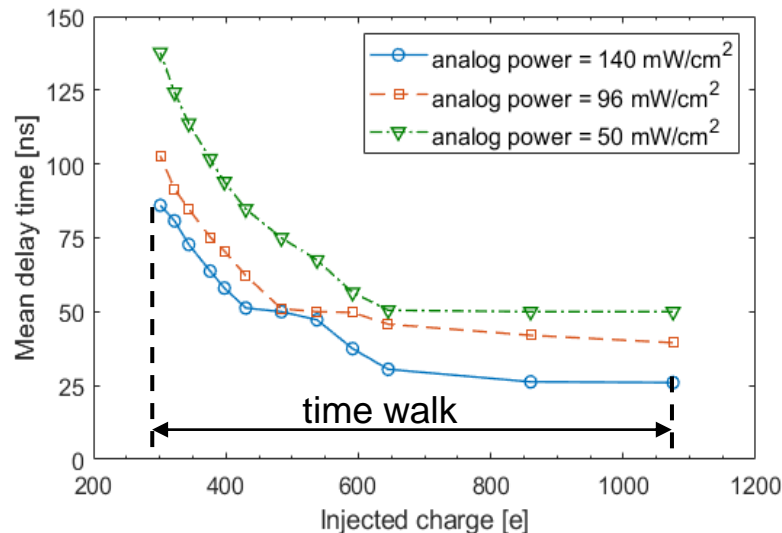
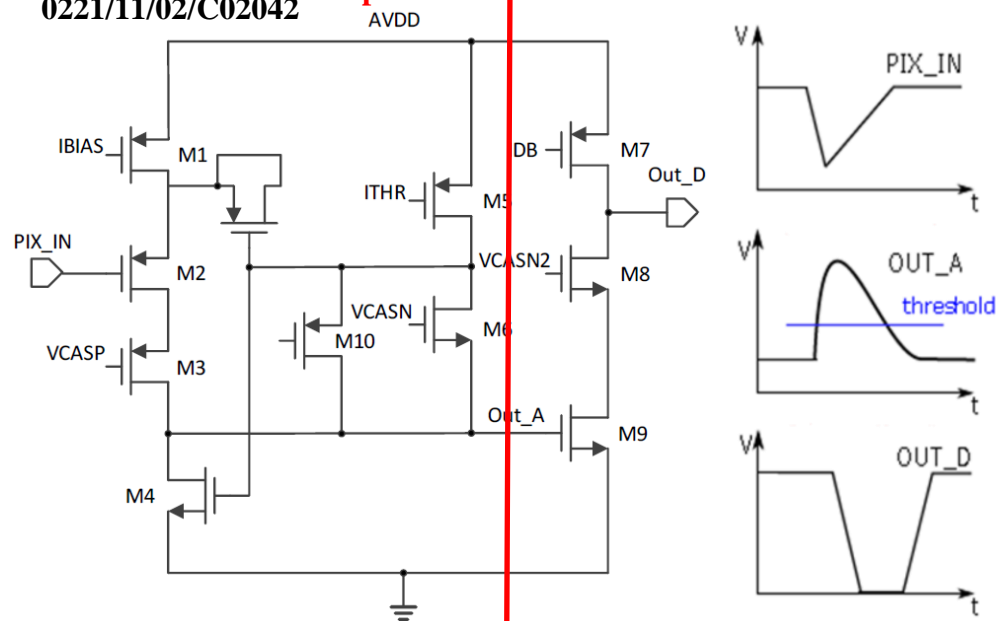


**TaichuPix-3**  
(15.9 × 25.7 mm<sup>2</sup>)

# Pixel architecture – Analog

D. Kim et al. DOI 10.1088/1748-0221/11/02/C02042

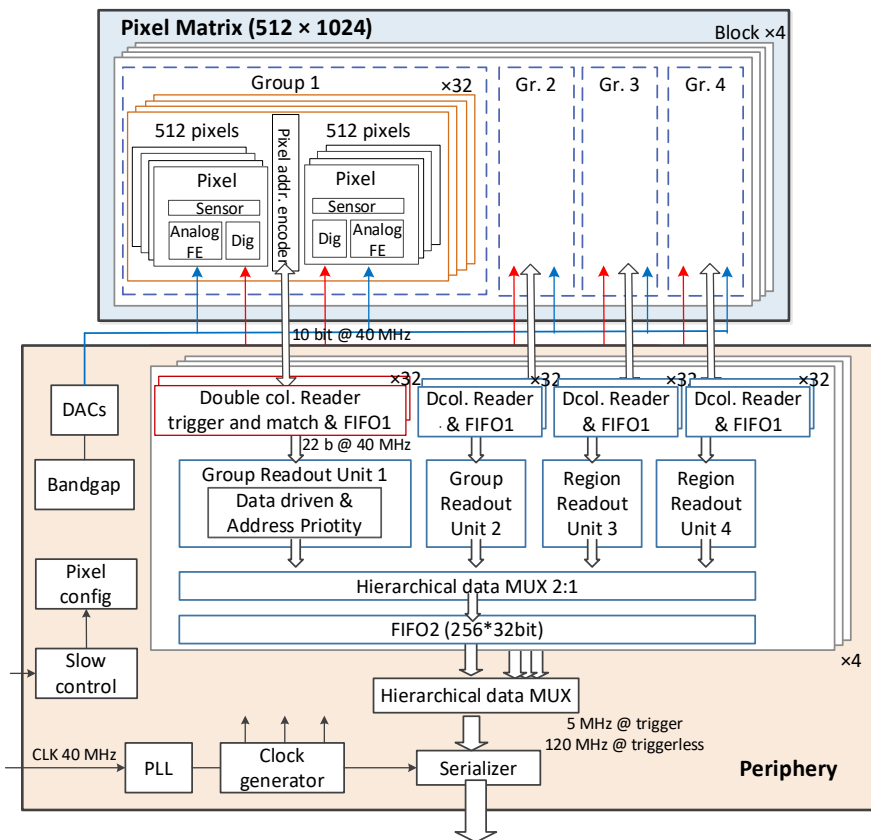
Amplification Discrimination



Delay time of FASTOR with respect to the pulse injection vs. injected charge. The delay time was measured by the timestamp of a step of 25 ns.

- Digital-in-Pixel scheme: in pixel discrimination & register
- Pixel analog is derived from ALPIDE (and benefit from MIC4 for MOST1)
  - ✦ As most of ATLAS-MAPS sensors' scheme
- Biasing current has to be increased, for a peaking time of ~25ns
  - ✦ for 40MHz BX @ Z pole
- Consequence:
  - ✦ Power dissipation increased
  - ✦ Faster CIS process has to be used
    - With faster charge collection time, otherwise only fast electronics is of no meaning

# TaichuPix sensor architecture



- **Pixel 25  $\mu\text{m}$   $\times$  25  $\mu\text{m}$**

- Continuously active front-end, in-pixel discrimination
- Fast-readout digital, with masking & testing config. logic

- **Column-drain readout for pixel matrix**

- Priority based data-driven readout
- Time stamp added at end of column (EOC)
- Readout time: 50 ns for each pixel

- **2-level FIFO scheme**

- L1 FIFO: de-randomize the injecting charge
- L2 FIFO: match the in/out data rate between core and interface

- **Trigger-less & Trigger mode compatible**

- Trigger-less: 3.84 Gbps data interface
- Trigger: data coincidence by time stamp, only matched event will be readout

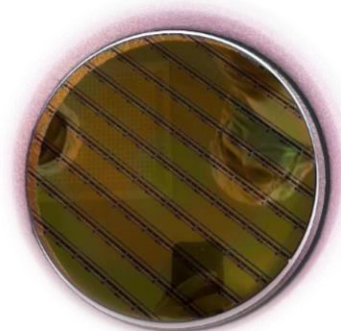
- **Features standalone operation**

- On-chip bias generation, LDO, slow control, etc.

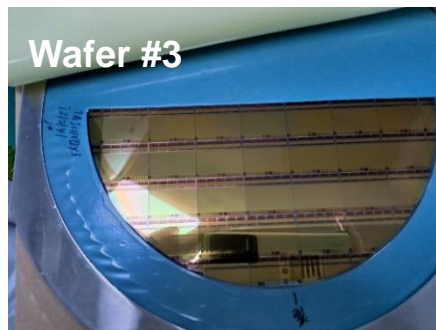
# Full size sensor TaichuPix-3

- 12 TaichuPix-3 wafers produced from two rounds

- Wafers thinned down to 150 μm and diced



8-inch wafer

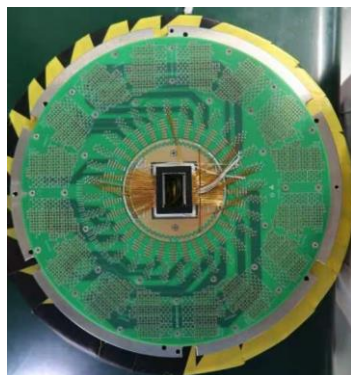


Wafer after thinning and dicing

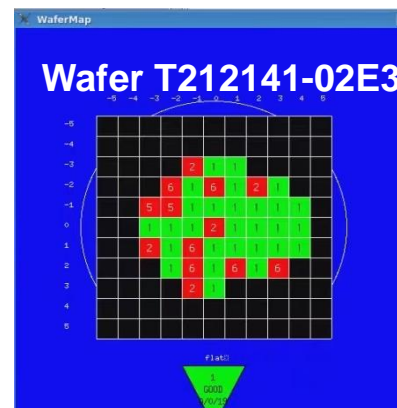


Thickness after thinning

- Wafers tested on probe-station → chip selecting & yield evaluation



Probe card for wafer test

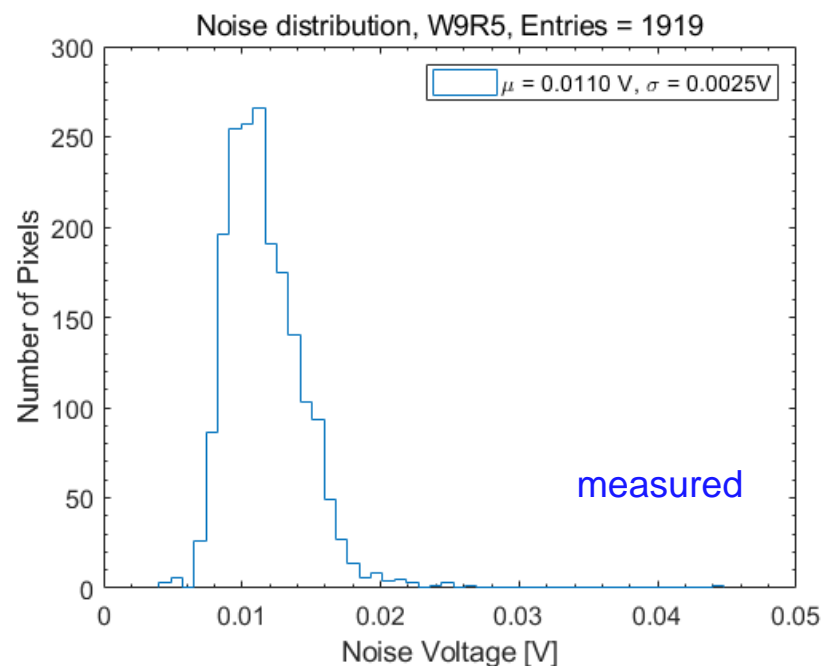
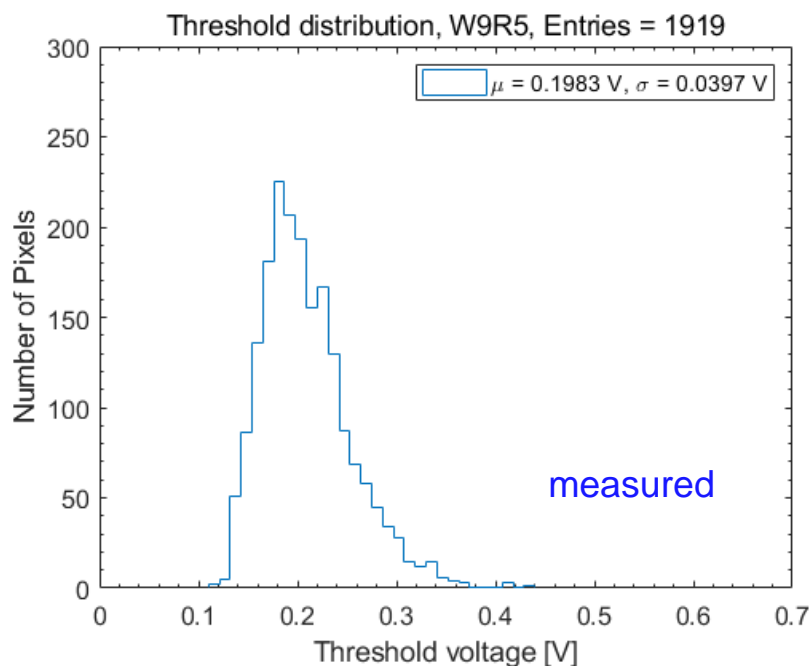


An example of wafer test result (yield ~67%)



# Threshold and noise of TaichuPix-3

- Pixel threshold and noise were measured with selected pixels
  - Average threshold  $\sim 215 e^-$ , threshold dispersion  $\sim 43 e^-$ , temporal noise  $\sim 12 e^-$  @ nominal bias setting
  - S-curve method was used to test and extract the noise and the threshold

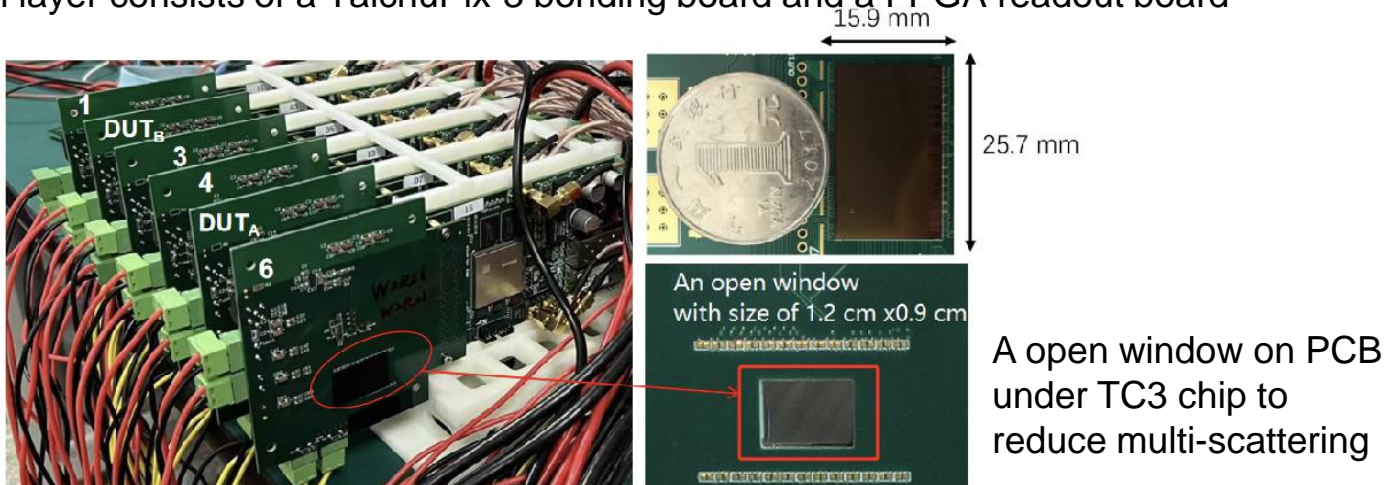


- Power dissipation of  $89 \sim 164 \text{ mW/cm}^2$  tested @ 40MHz clk with different biasing condition

# TaichuPix-3 telescope

- **The 6-layer of TaichuPix-3 telescope built**

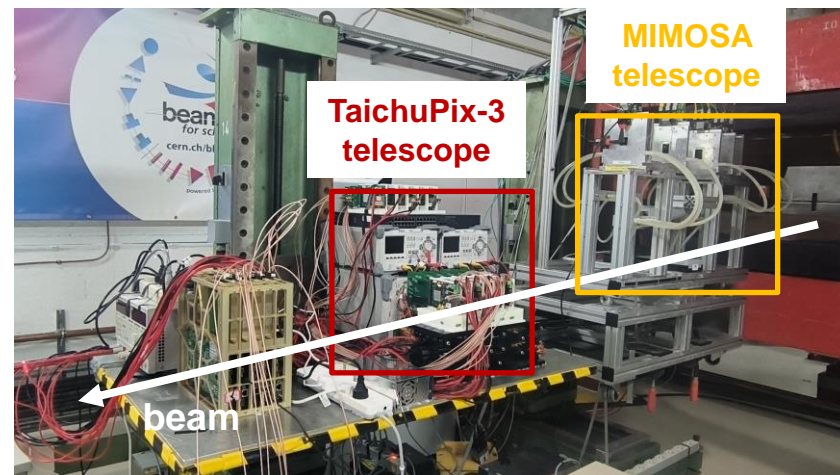
- Each layer consists of a TaichuPix-3 bonding board and a FPGA readout board



6-layer TaichuPix-3 telescope

- **Setup in the DESY testbeam**

- TaichuPix-3 telescope in the middle
- Beam energy: 4 GeV mainly used
- Tests performed for different DUT (Detector Under Test)



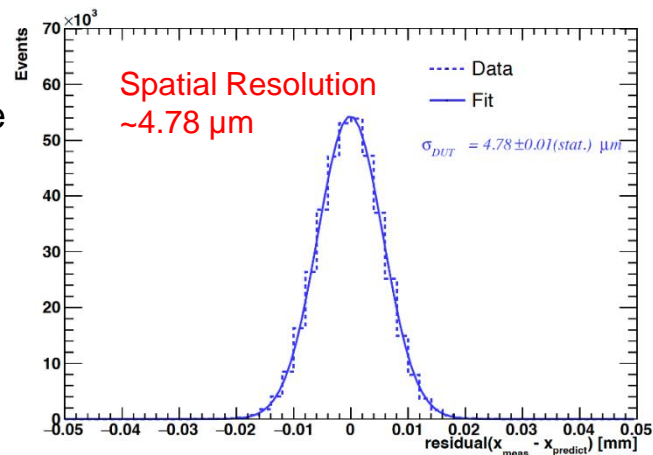
# TaichuPix-3 beam test result

## Spatial resolution

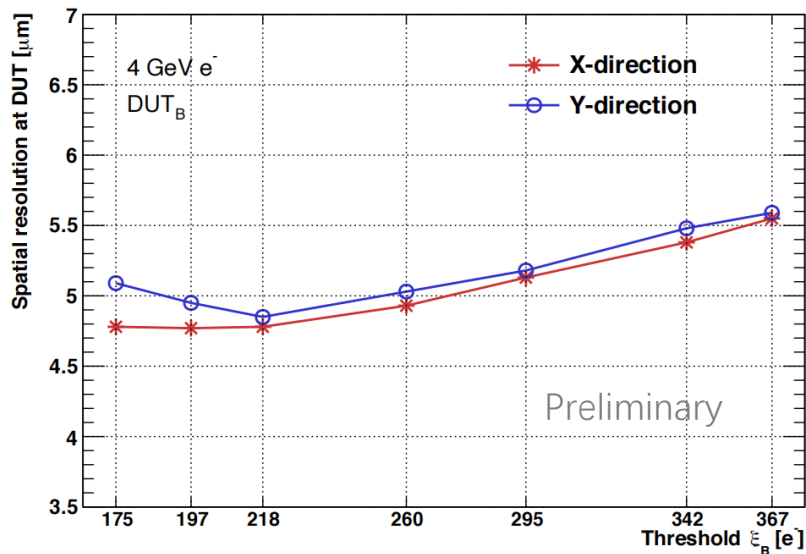
- Gets better when decrease the pixel threshold, due to the increased cluster size
- A resolution  $< 5 \mu\text{m}$  achieved, best resolution is  $4.78 \mu\text{m}$

## Detector efficiency

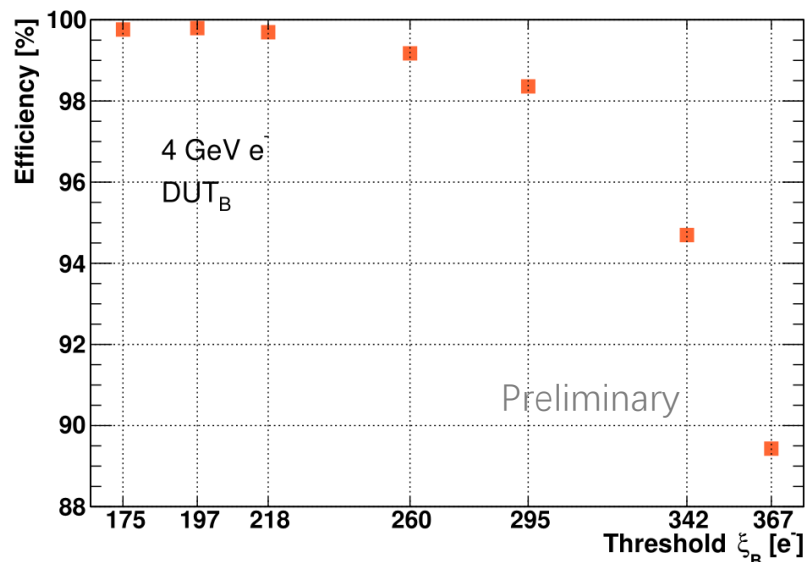
- Decreases with increasing the threshold, **detection efficiency  $> 99.5\%$**  at threshold with best resolution



Distribution of residual X



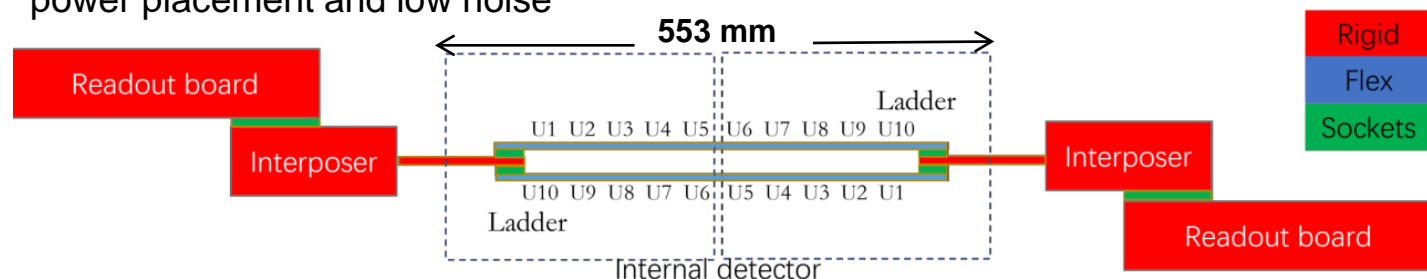
Spatial resolution vs. pixel threshold



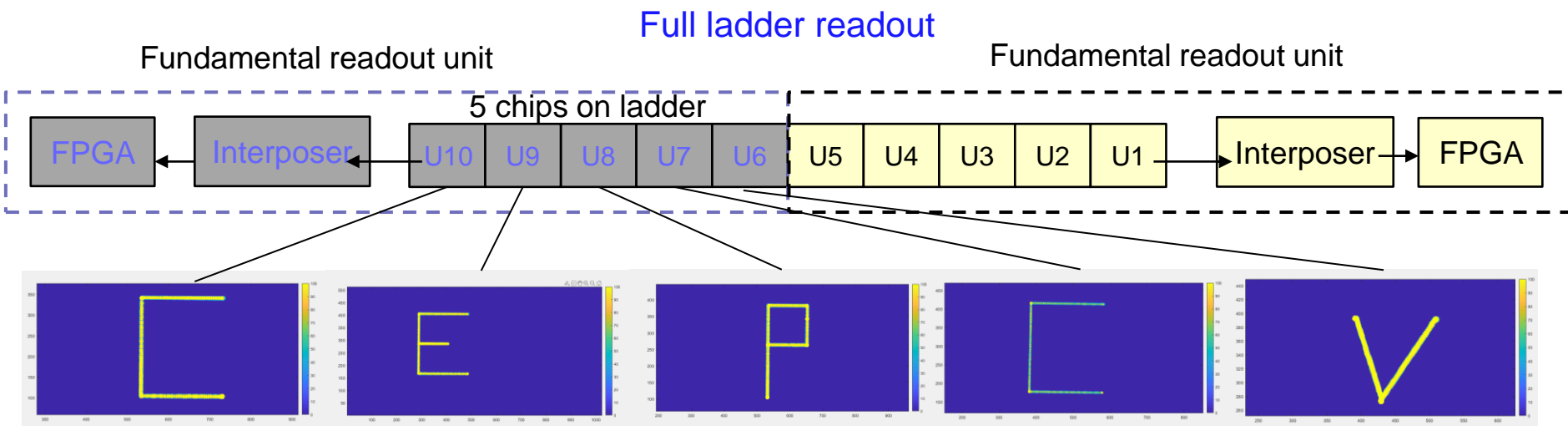
Detection efficiency vs. pixel threshold

# Ladder readout design

- **Detector module (ladder) = 10 sensors + readout board + support structure + control board**
  - Sensors are glued and wire bonded to the flexible PCB, supported by carbon fiber support
  - Signal, clock, control, power, ground will be handled by control board through flexible PCB
- **Challenges**
  - Long flex cable → hard to assemble & some issue with power distribution and delay
  - Limited space for power and ground placement → bad isolation between signals
- **Solutions**
  - Read out from both ends, readout system composes of three parts, careful design on power placement and low noise



# Laser test result of ladder



Laser tests on 5 TaichuPix chip on a full ladder  
 (“CEPCV” pattern by scanning laser on different chips on ladder)

- **A full ladder includes two identical fundamental readout units**
  - Each contains 5 TaichuPix chips, a interposer board, a FPGA readout board
  
- **Functionality of a full ladder fundamental readout unit was verified**
  - Configuring 5 chips in the same unit
  - Scanning a laser spot on the different chips with a step of 50  $\mu\text{m}$ , clear and correct letter imaging observed
  - **Demonstrating 5 chips working together → one ladder readout unit working**

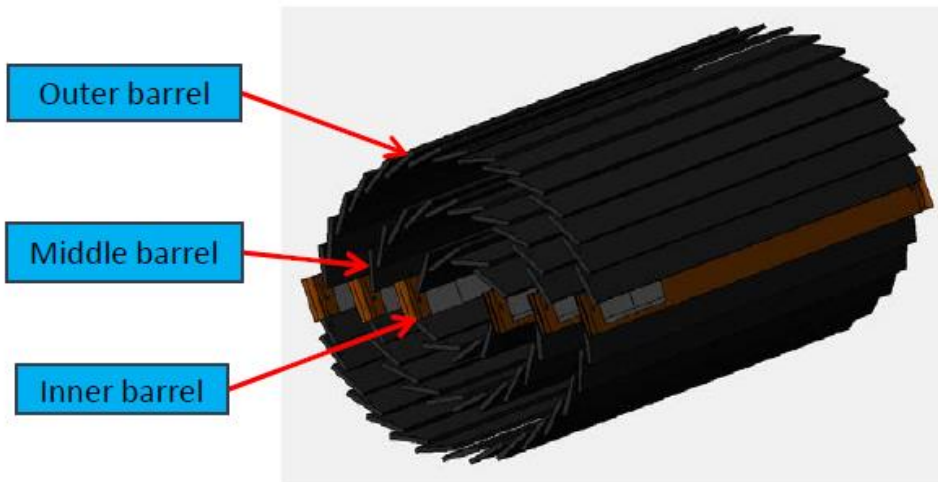
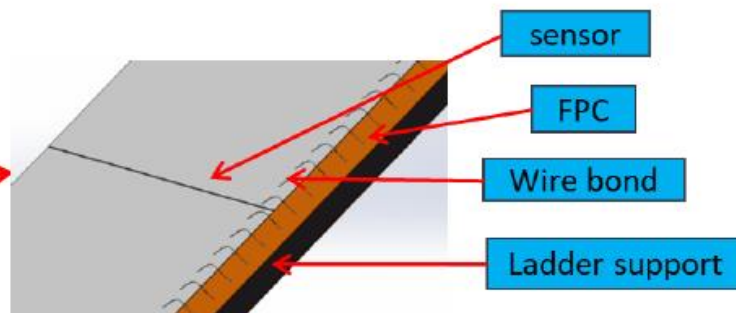
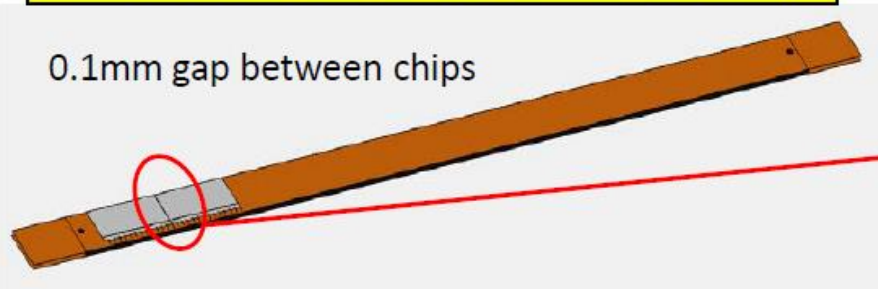
# VTX mechanical concept

**Sensor chip** : 16.8\* x 25.6 mm (2\* mm margin at one side for wire bonding)

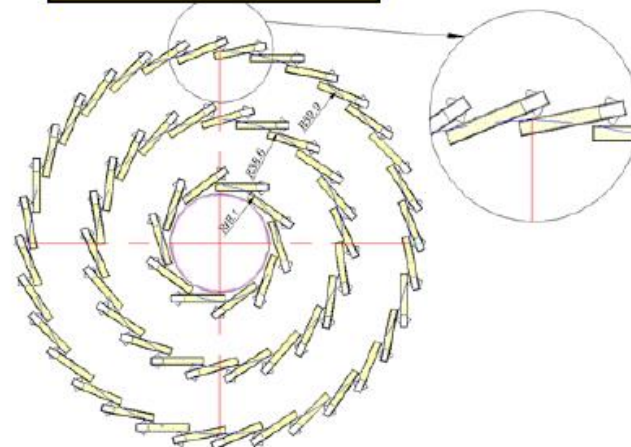
**Ladder**: support + sensors + FPCs, sensors and FPCs on doubled sides of the ladder.

The double sided Ladder (17.4 \*x 272.9 mm)

0.1mm gap between chips



Overlapped area



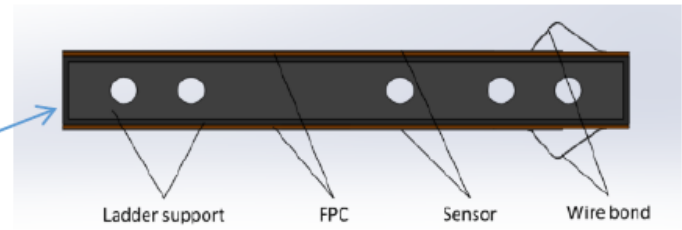
# Ladder support design

With the FEA assistance, compared different optional designs, optimized and finalized the details of the official design.

**Material:** CFRP.

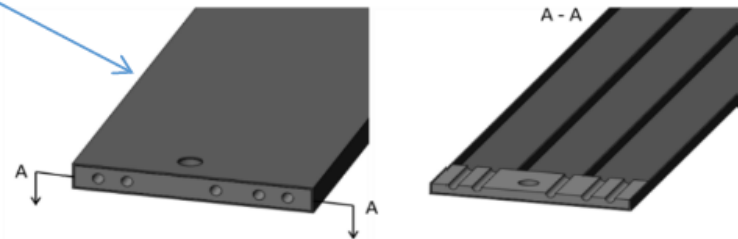
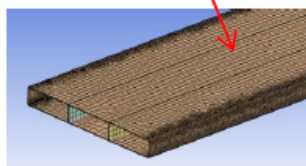
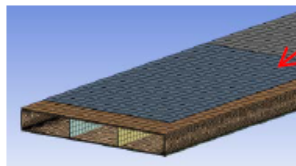
**Size:** 272.9 x 17.4 x 2 mm (L x W x H ).

ladder support structure



FEA results of static deformation of ladder support

Laminate thickness	Weight of the support tube (gram)	Deformation (μm)	
		Ladder (under self-weight)	Ladder support (under full load)
120 μm	2.0	4.9	6.8



Fabrication process test



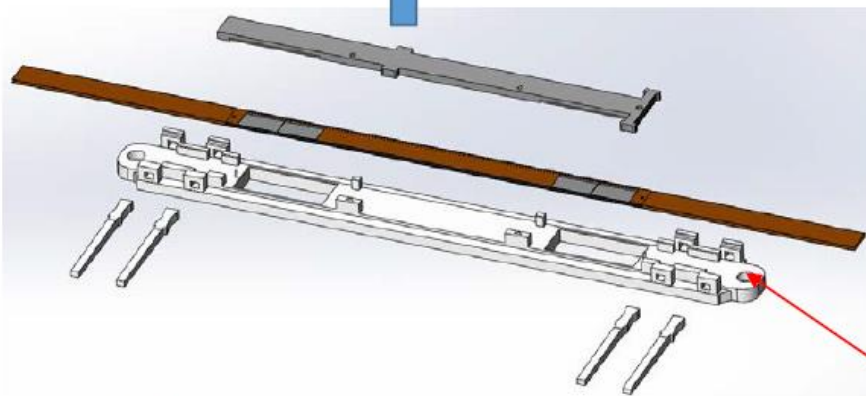
Aiming to reduce material, the CFRP laminate need to be very thin, to make the structure with such a length and small section by the thin laminate is challenging.

# Tooling design for ladder assembly

To assemble the double-sided ladder is a complex and delicate work.

- Assembly scheme and procedures were fully considered.
- Tooling for specific process were designed.

Tooling for mounting module on the reverse side of a ladder



2023/6/19

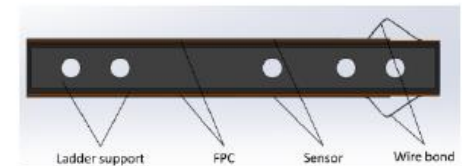
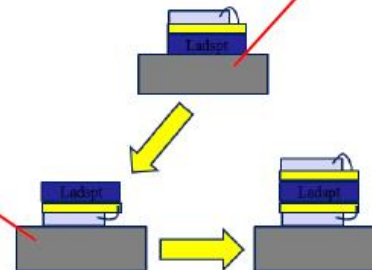
Sensor pickup tool



Module fixation and protection components



Vacuum plate for flex and CFRP support fixation



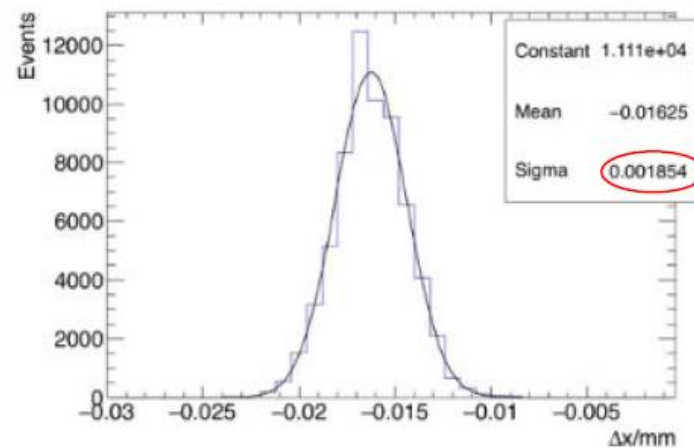
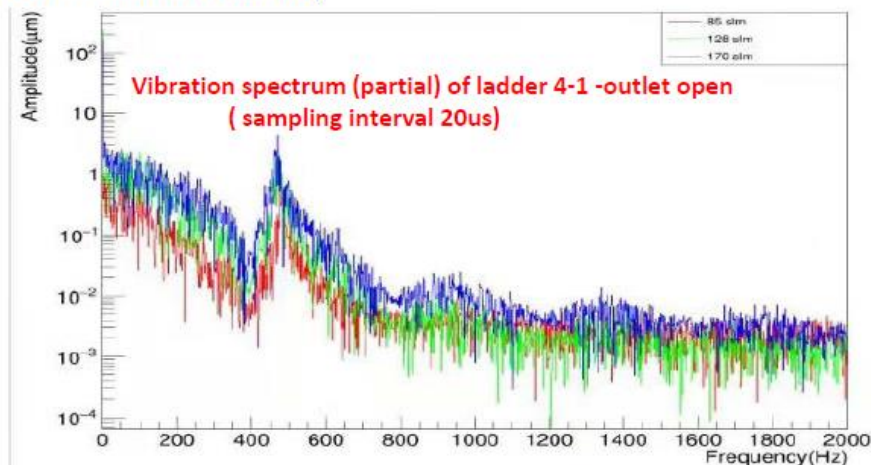
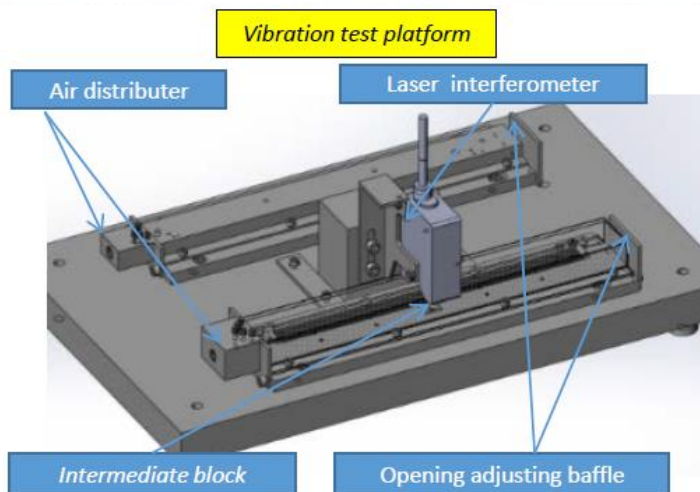
8



# Ladder vibration test

Tested the CFRP ladder support under different estimated air flow rate, and analyzed the result :

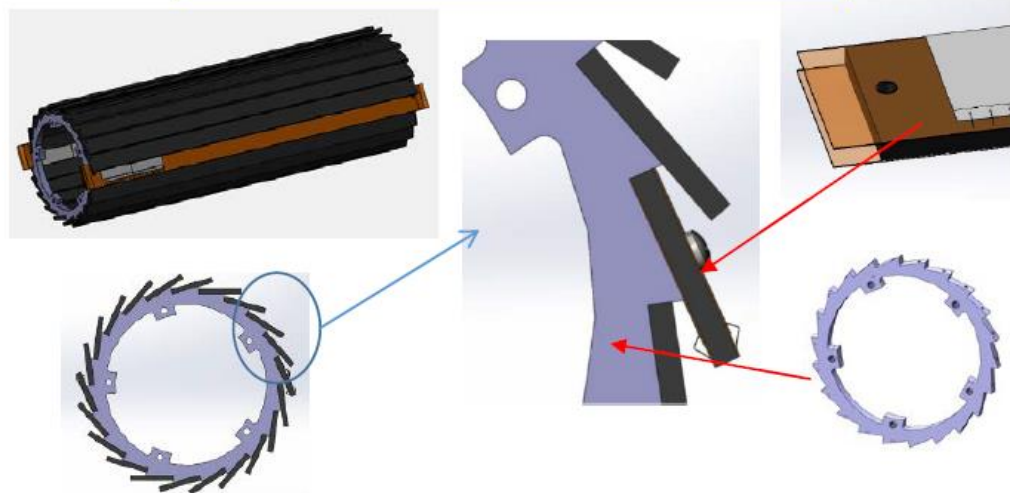
- the vibration spectrum (*sample as below*)
- *statistic analysis of the results (Gaussian distribution)*



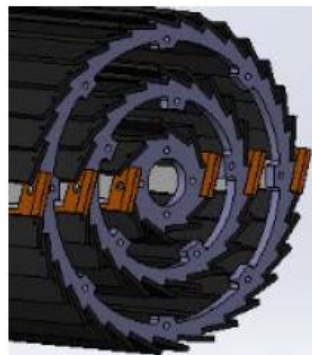
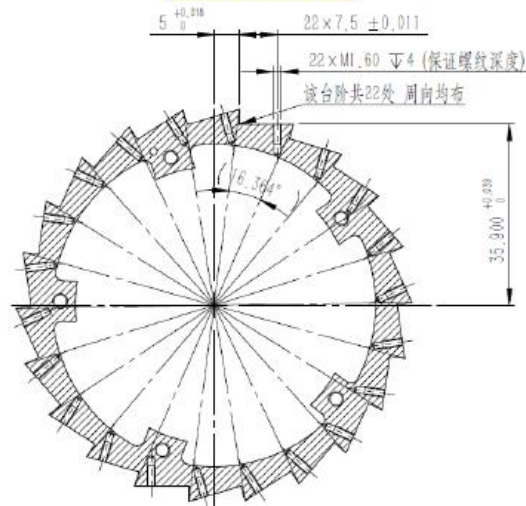
The max vibration amplitude is  $1.9 \mu\text{m}$ , which is much smaller than the detector resolution. The result shows the ladder support has enough rigidity under estimated air flow.

# Ladder fixation on barrel

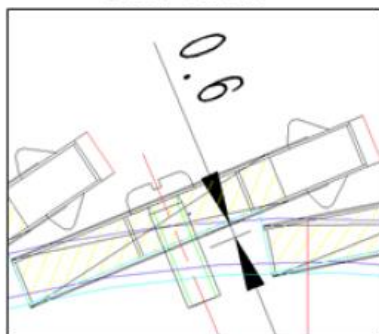
Sides constraint/alignment + screw tighten



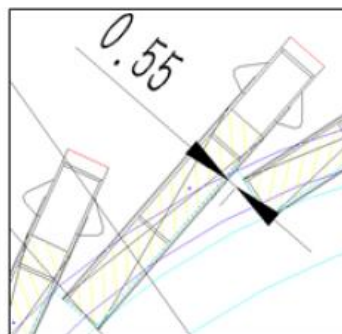
Side ring



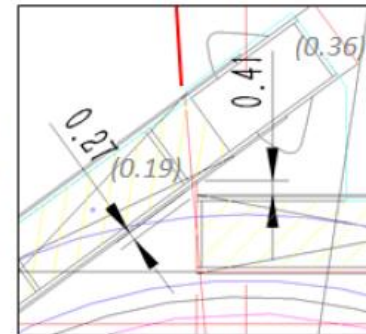
Outer barrel



Middle barrel



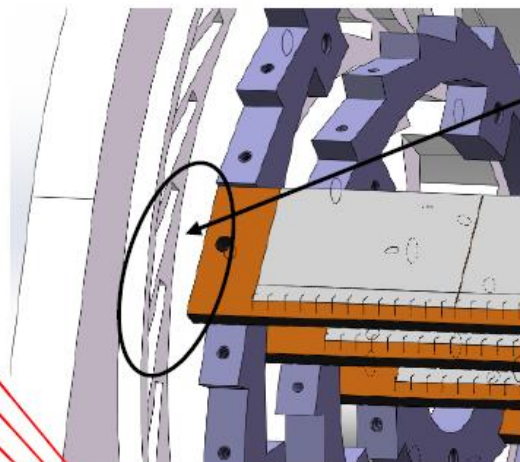
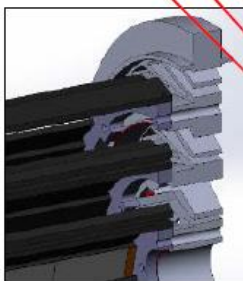
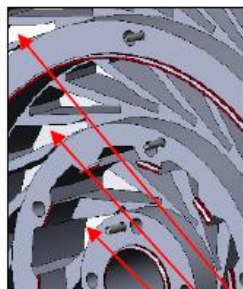
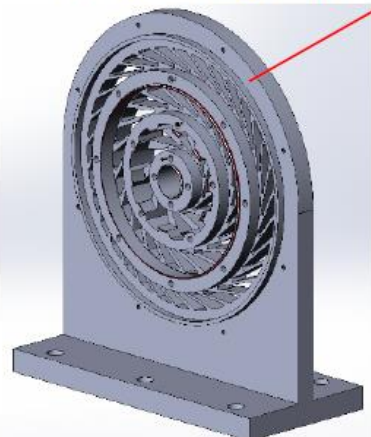
Inner barrel



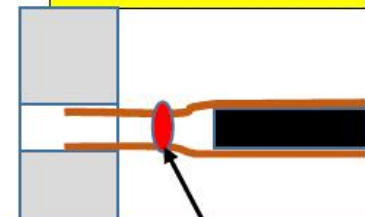
- The barrel is a tight structure with very small gap between ladders, assembly is challenging.
- All support parts need high accuracy to assemble a precise barrel and the VTXD that has three barrels coaxially mounted.

# Barrels fixation on the brackets

Barrels (side ring) locating on the main bracket: ring + pin

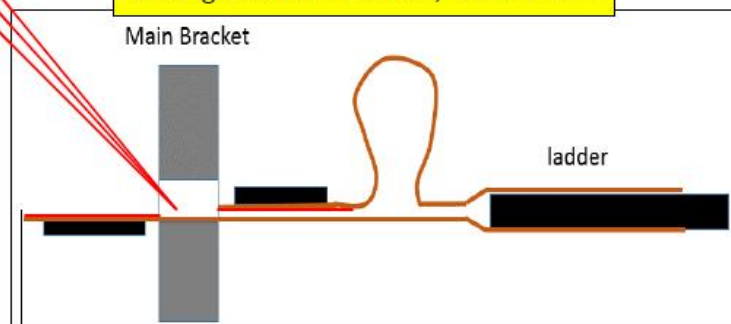


The convex ring provide a transition region for flex routing.

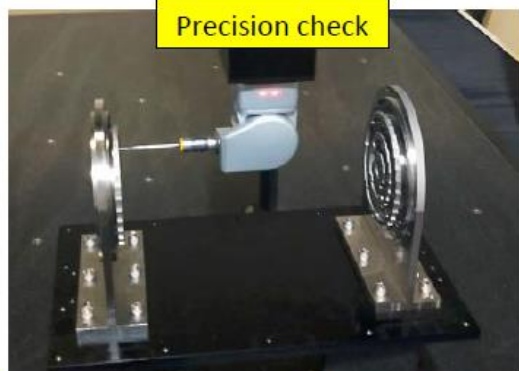


Glue adjacent flex to enable routing and for protection.

Slot holes on the bracket: pass flex through bracket in order, ventilation



Precision check



Flex



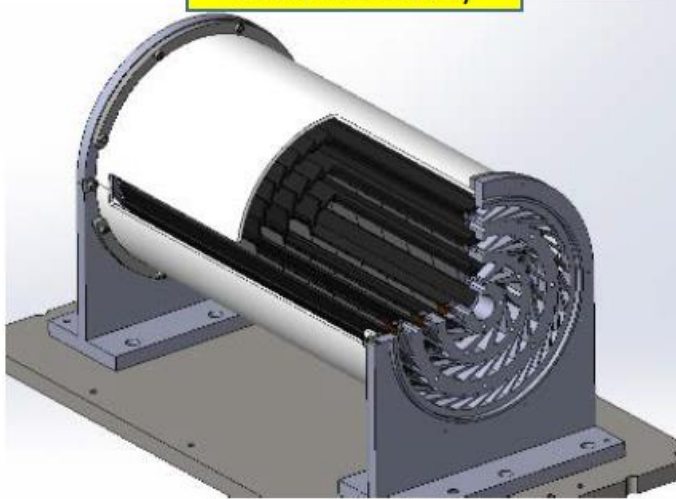
The metal material used for the support brackets and side rings of the prototype is **not necessary for the detector**, it is only for the beam testing and transportation.

2023/6/19

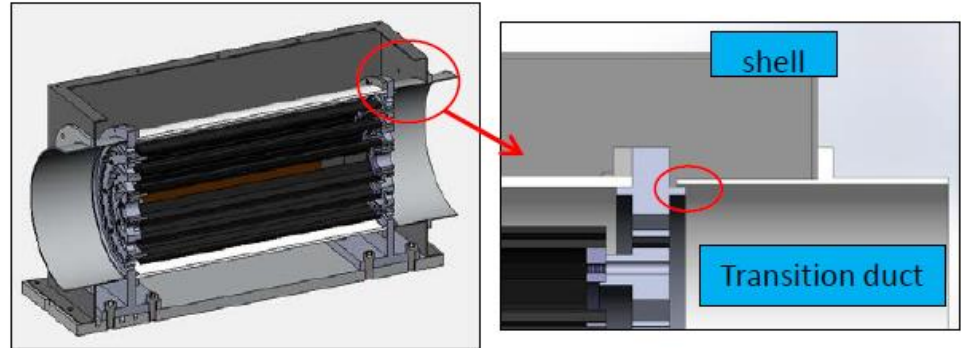
11

# Overall structure design of the VTXD prototype

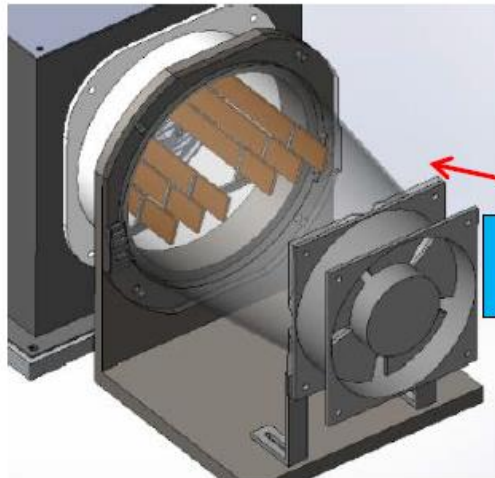
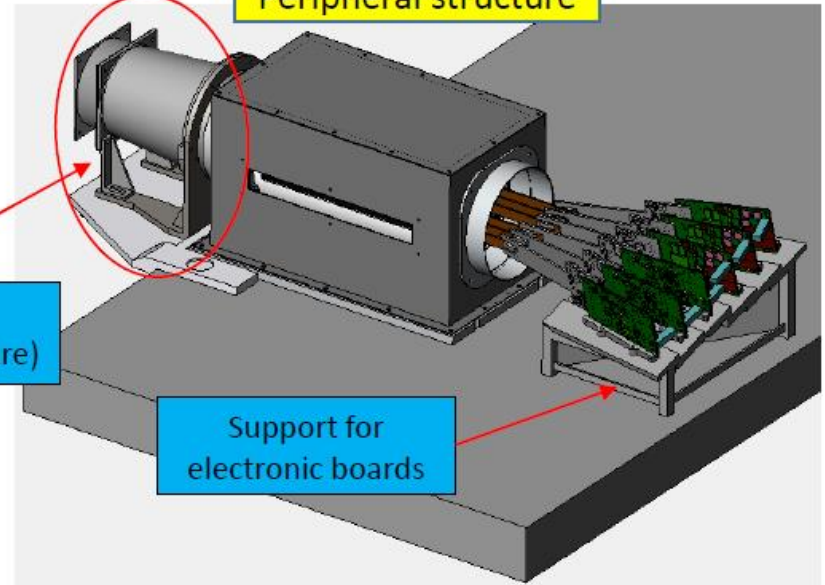
VTXD assembly



VTXD box (vent, vibration-isolation, protection)



Peripheral structure



fan and duct  
(independent structure)

# Prototype cooling

The cooling for prototype were designed based on the sensor power dissipation:

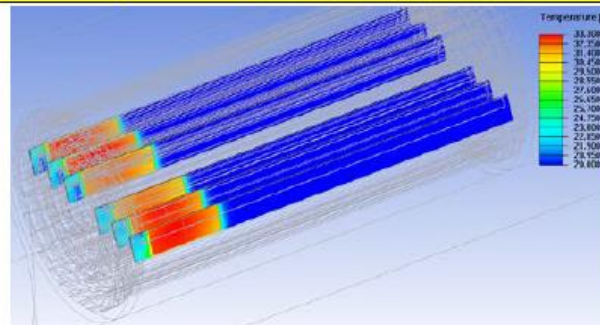
- air cooling (fan selected)
- ventilation and cooling ducts design
- cooling simulation

Temperature of the chips was monitored during the beam test. Verified:

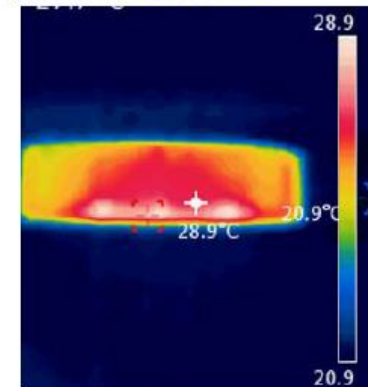
- reasonable cooling design (real temperature is within the simulation)
- good vibration isolation - Vibration induced by cooling does not affect the detector resolution, benefiting from the non-contact independent assembly design.



Prototype cooling simulation: Max 33.3 °C

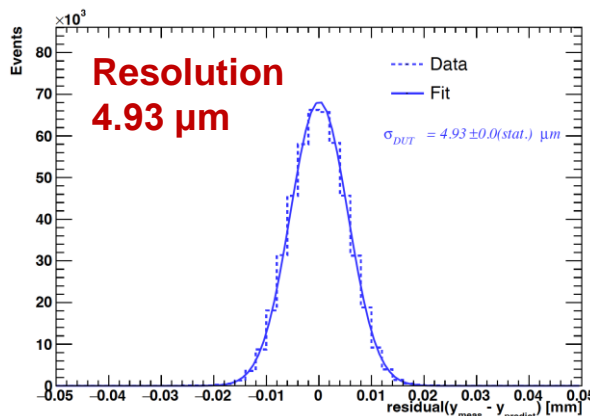
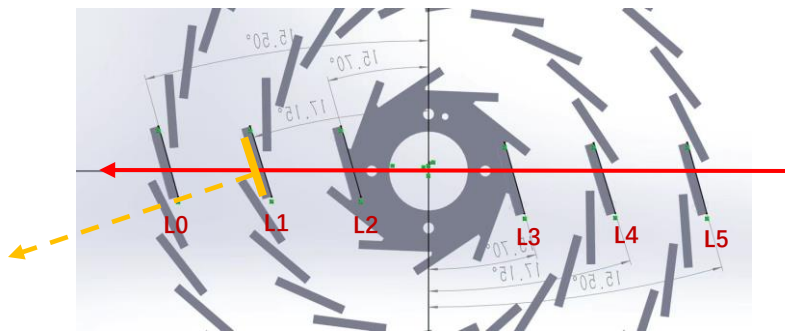
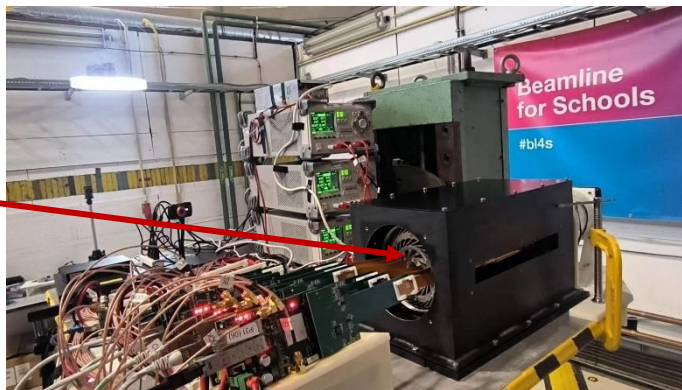
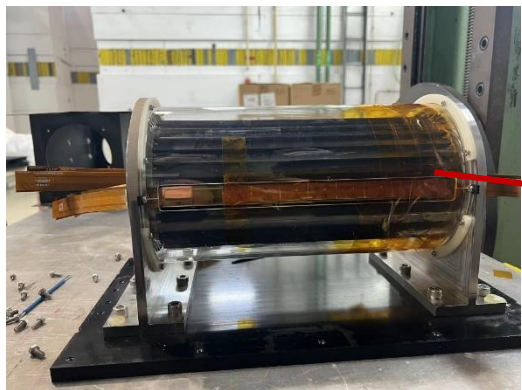


Chip temperature under cooling during beam test:  
Max 28.9 °C



# Detector prototype

- **6 double-sided layers assembled on the detector prototype**
  - 12 flex boards with two TaichuPix-3 chips bonded on each flex
  - Readout boards on one side of the detector



Preliminary offline results indicate a good performance for the vertex detector prototype.

	L0-L1	L1-L2	L2-L3	L3-L4	L4-L5
L(mm)	21.2	20.6	37.46	20.6	21.2

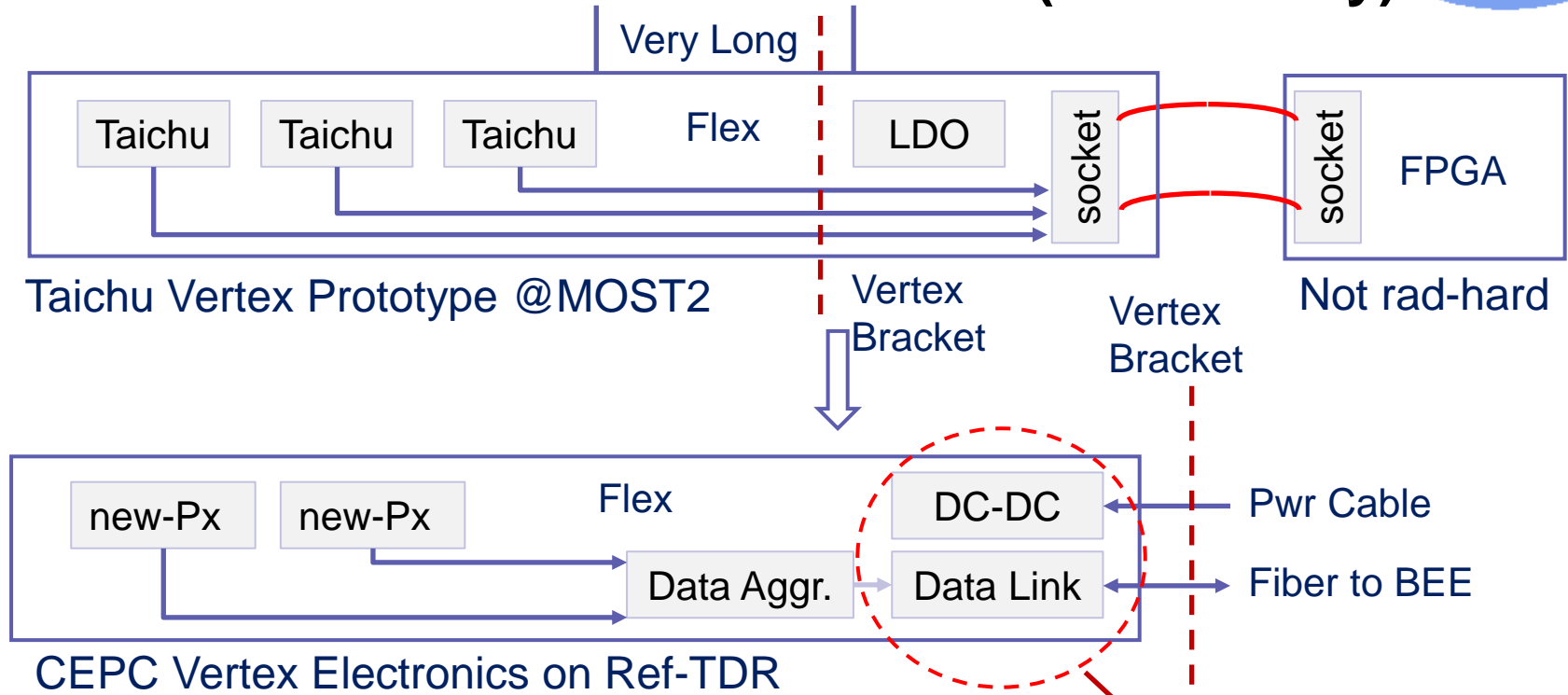
# From CDR towards Ref-TDR – Preliminary Calculation



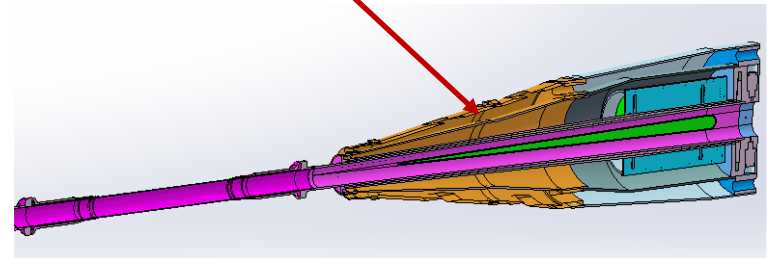
		Hit density (Hits/cm <sup>2</sup> /BX)	Bunch spacing (ns)	Hit rate (M Hits/cm <sup>2</sup> )	Hit Pix rate (M Px/cm <sup>2</sup> )	Hit rate/chip (MHz)	Data rate@triggerless (Gbps)	Pixel/bunch	FIFO Depth @3us rg latency	Data rate@trigger (Mbps)
CDR	Higgs	2.4	680	3.53	10.59	34.62	1.1	23.5	103.9	105.28
	W	2.3	210	10.95	32.86	107.44	3.4	22.6	322.3	101.248
	Z	0.25	25	10	30	98.1	3.1	2.4	294.3	53.76
TDR	Higgs	0.81	591	1.37	4.11	13.44	0.43	7.96	40.4	0.017
	W	0.81	257	3.16	9.45	30.90	0.98	7.96	92.8	3.6
	Z	0.45	23	19.6	58.7	191.9	5.9	4.4	575	118

- **TDR raw hit density: Higgs 0.54, Z 0.3; Safety factor: TDR 1.5, CDR 10;**
- **Cluster size: 3pixels/hit (@Twjz 180nm, EPI 18~25um)**
- **Area: 1.28cm\*2.56cm=3.27cm<sup>2</sup> (@pixel size 25um\*25um)**
- **Word length: 32bit/event (@Taichu's scale, 512\*1024 array)**
- **Trigger rate: 20kHz@CDR, 120kHz@Z, 10Hz@Higgs, 2kHz@W TDR**
  - Trigger latency: 3us(L0 fast trigger expected), Error window: 7 bins
  - FIFO depth: @3us \* hit rate/chip
  - Data rate=pixel/bunch\*trigger rate\*32bit\*error window

# Towards the CEPC Detector Ref-TDR (Preliminary)



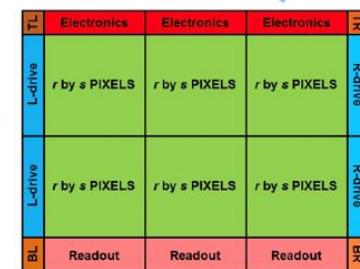
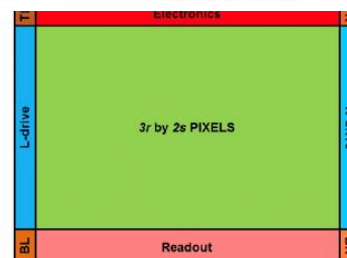
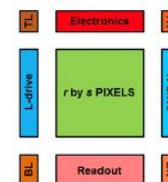
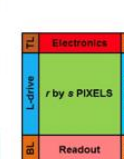
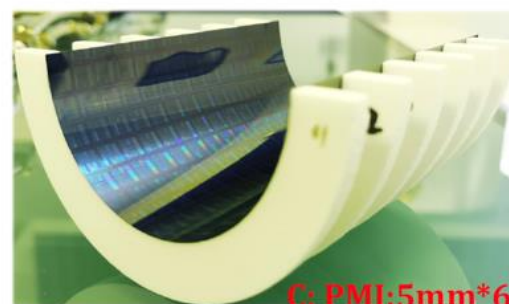
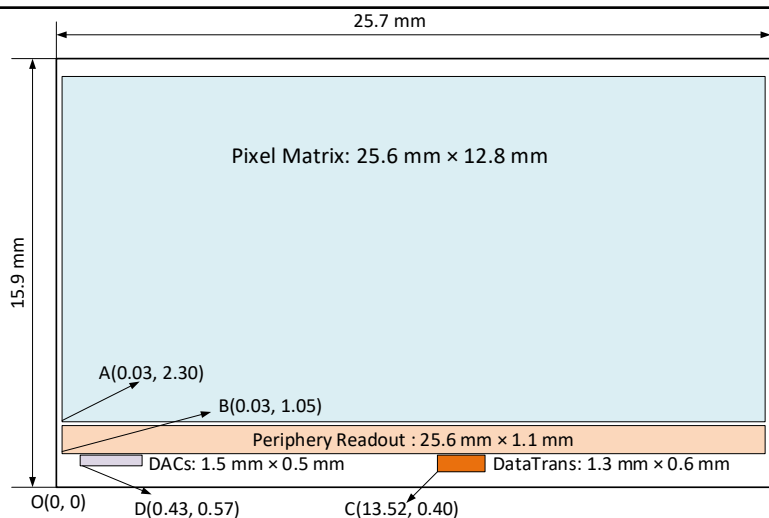
- Q: height & area & power limit for power & optical module
- Q: trying to be also triggerless readout
- Q: stitching technology is proposed to be the baseline scheme





# From R&D towards the Ref-TDR

	Matrix	Periphery	DataTrans.	DACs	Total Power
太初芯片 @ triggerless (CDR)	304 mW	135 mW	206 mW	10 mW	655 mW
65nm 芯片 @ 1 Gbps/chip (TDR LowLumi)	60 mW	80 mW	36 mW	10 mW	186 mW



- 65nm will be the baseline technology (smaller pixel = spatial resolution)

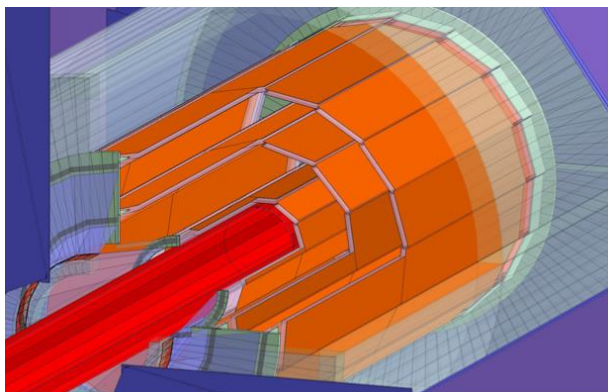
↳ Power saved by 1/3: 1.8V -> 1.2V

- Critical change:** needs to propose a full scheme for the stitching technology

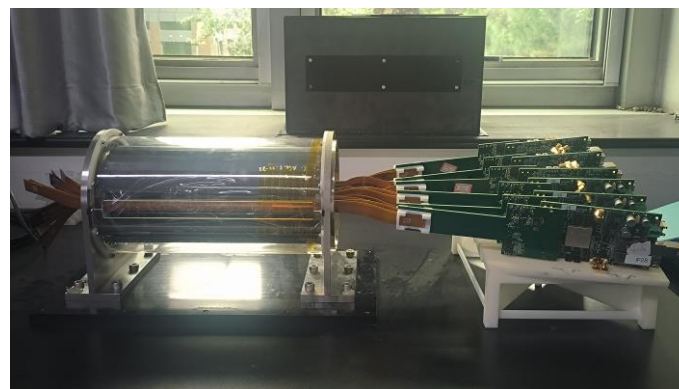
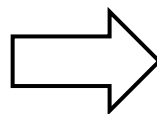
↳ Challenges: data rate, technology, power...

# Summary

- **The full-scale and high granularity pixel prototype, TaichuPix-3, has been designed and tested for CEPC VTX R&D**
  - Spatial resolution of 4.78/4.85  $\mu\text{m}$  measured with 4 GeV electron beam in DESY
  - Total ionization dose (TID) > 3 Mrad
- **Readout electronics for the sensor test and the ladder readout were developed**
  - Performed the sensor characterization in the lab successfully
  - Completed beam tests for the pixel sensor prototype and the vertex detector mechanical prototype



**Concept (2016)**



**1<sup>st</sup> Vertex detector prototype (2023)**

**Thank you very much for your attention !**

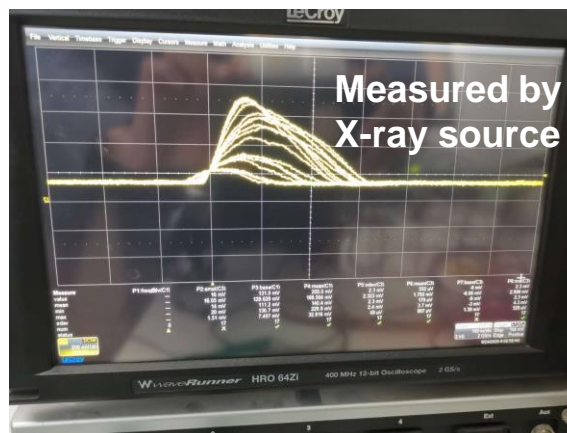
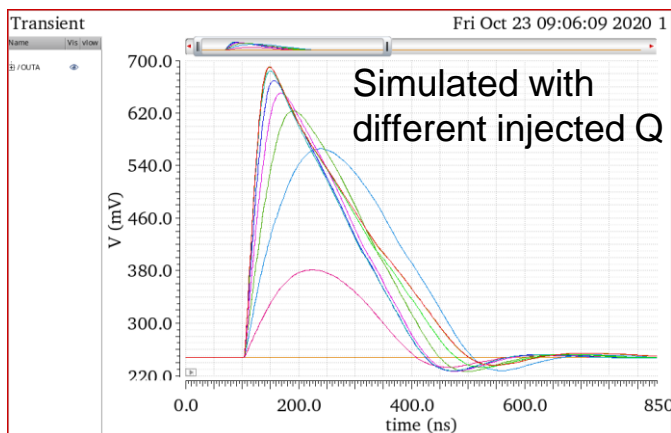
# TaichuPix-3 specification & performance

	Design specs.	Measured
Spatial resolution*	3~5 $\mu\text{m}$	4.8 $\mu\text{m}$ (best)
TID*	> 1 Mrad	> 3 Mrad
Pixel pitch	$\leq 25 \mu\text{m}$	25 $\mu\text{m}$
Chip size	$\sim 1.4 \times 2.56 \text{ cm}^2$	$1.59 \times 2.57 \text{ cm}^2$
Dead time	< 500 ns	$\sim 300 \text{ ns}$
Data rate	110 Mbps (trigger) 3.84 Gbps (triggerless)	Not tested Currently 160 Mbps tested
Power density	< 200 mW/cm <sup>2</sup>	89 – 164 mW/cm <sup>2</sup>

\*project indicator

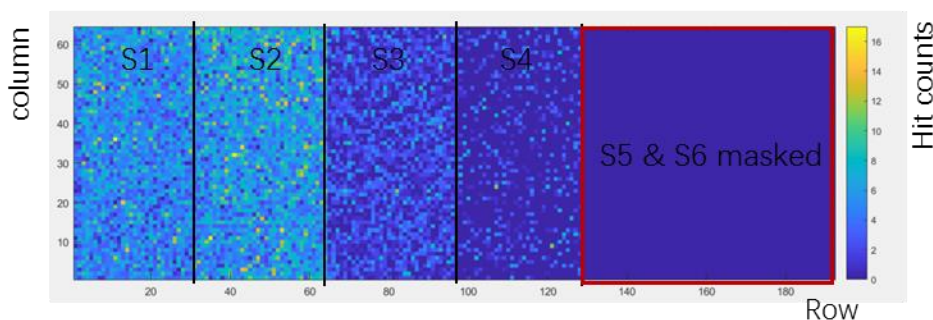
# Functionality of complete signal chain

- **Functionality of the complete signal chain** (including sensor, analog front-end, in-pixel logic readout, matrix periphery readout and data transmission unit) was firstly **proved** with X-ray, electron and laser sources.

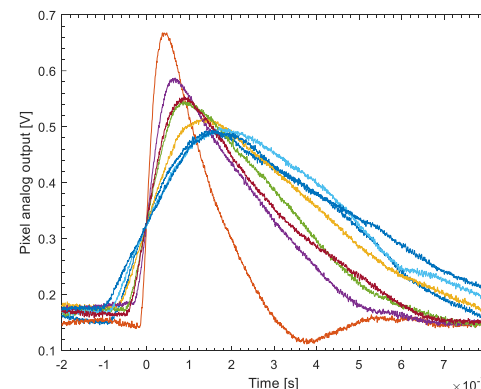


Measured results consistent with simulations in term of shape, amplitude

Pixel analog signals from simulation (left) and measurement (right)



Hit map of the TaichuPix-2 under X-ray from the X-tube for 5 min.



Analog output of one pixel under  $^{90}\text{Sr}$  exposure

# Hitmap

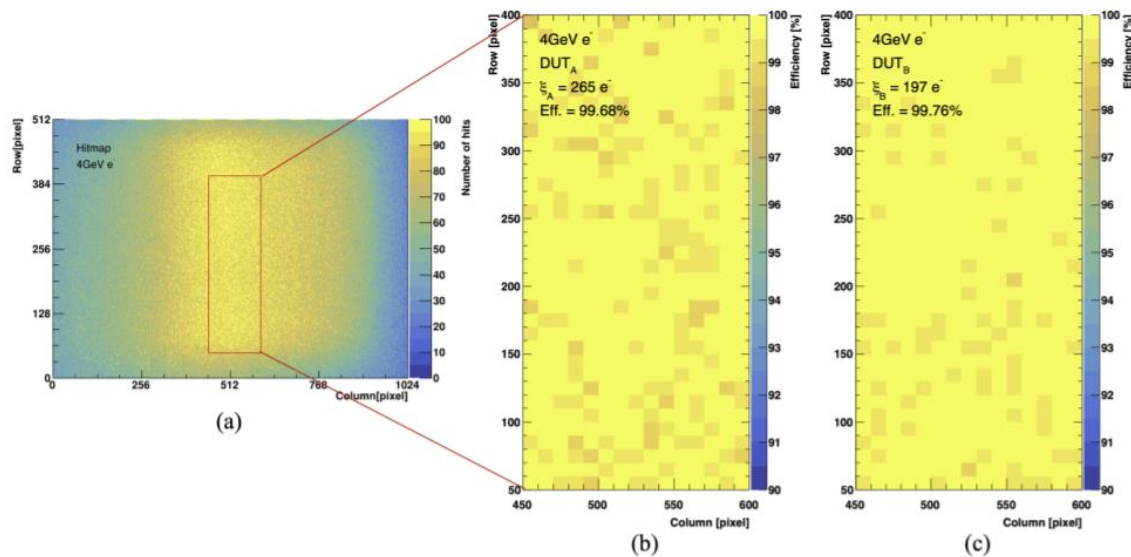
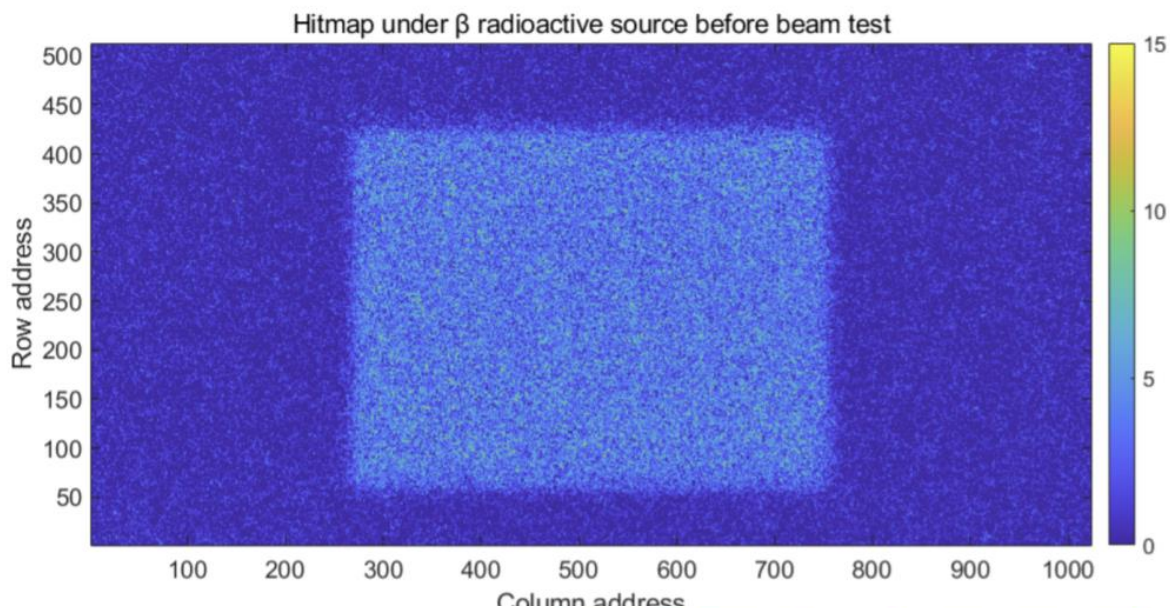


Figure 12: (a) The hitmap of one example DUT under 4 GeV electron beam. The pixels inside the red box are used to calculate the average efficiency of every  $10 \times 10$  pixels. (b) (c) The efficiency map of DUT<sub>A</sub> and DUT<sub>B</sub> at the minimum threshold.

# Cluster size

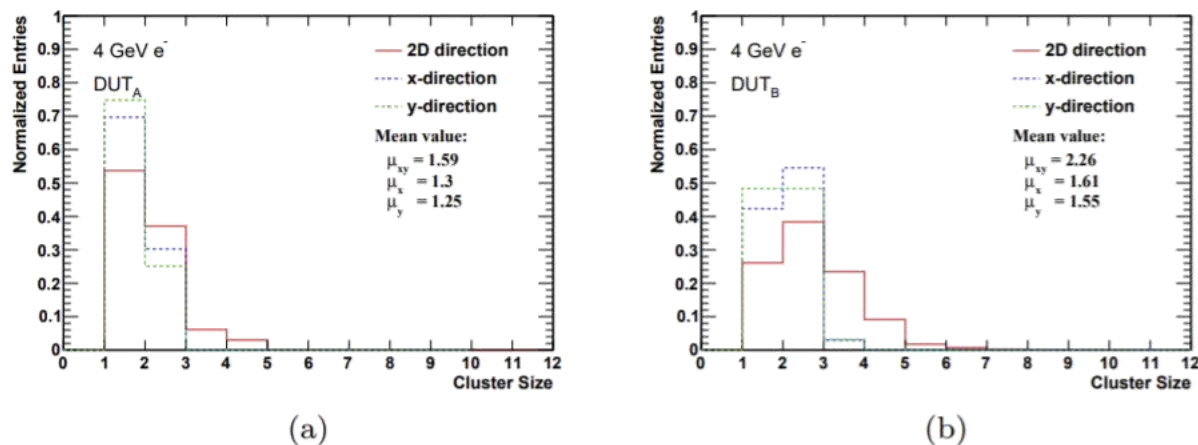


Figure 6: The cluster size distribution for  $DUT_A$  with  $\xi_A = 265e^-$  (a) and  $DUT_B$  with  $\xi_B = 175e^-$  (b), shown in the 2D detector plane direction and 1D projections along the  $x$ -direction (row direction of the sensor) and  $y$ -direction (column direction of the sensor).

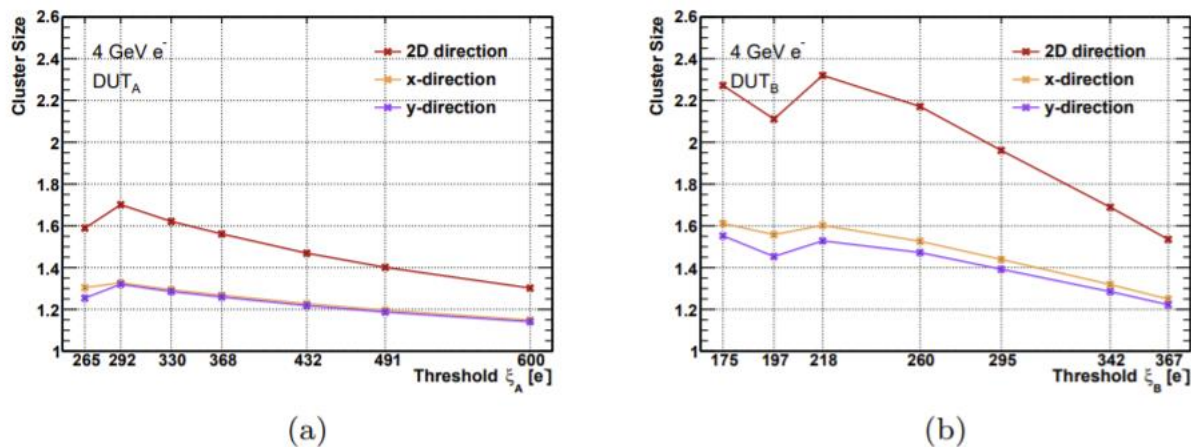
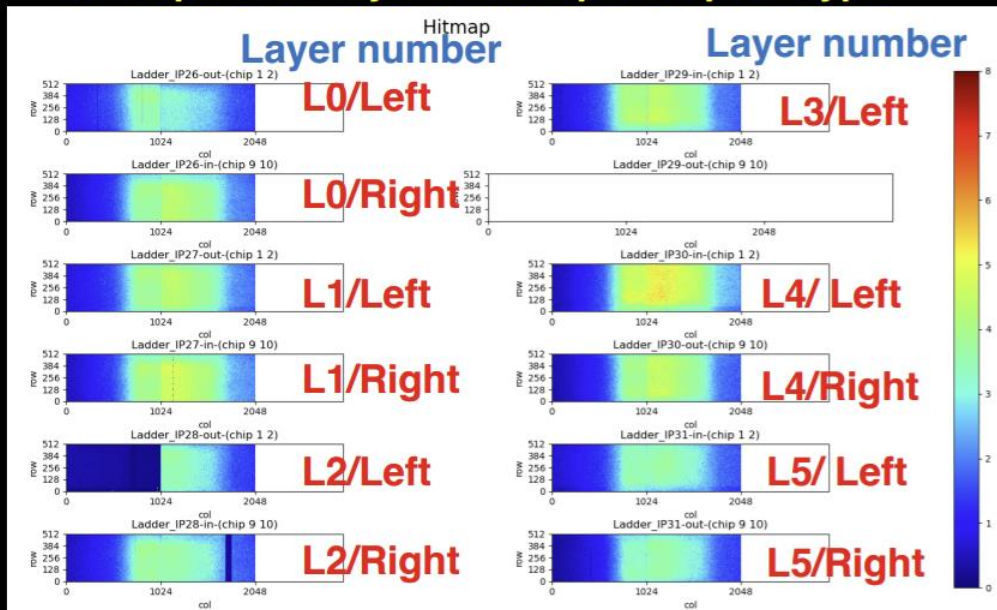


Figure 7: Average cluster size of  $DUT_A$  (a) and  $DUT_B$  (b) as a function of threshold  $\xi$ , shown in the 2D detector plane and 1D projections along  $x$ -direction and  $y$ -direction.

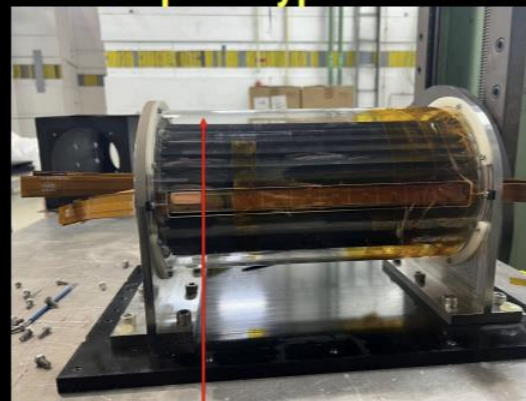
# Test beam @ DESY for detector prototype

- Six double-side ladders installed on the vertex detector prototype for DESY testbeam
  - 12 flex PCB, 24 Taichupix chips installed on detector prototype
  - Beam spot ( $\sim 2 \times 2$ cm) is visible on detector hit map
  - Record about one billion tracks in two weeks

## Hit maps of all layers taichupix on prototype



## Detector prototype in testbeam



Electron beam

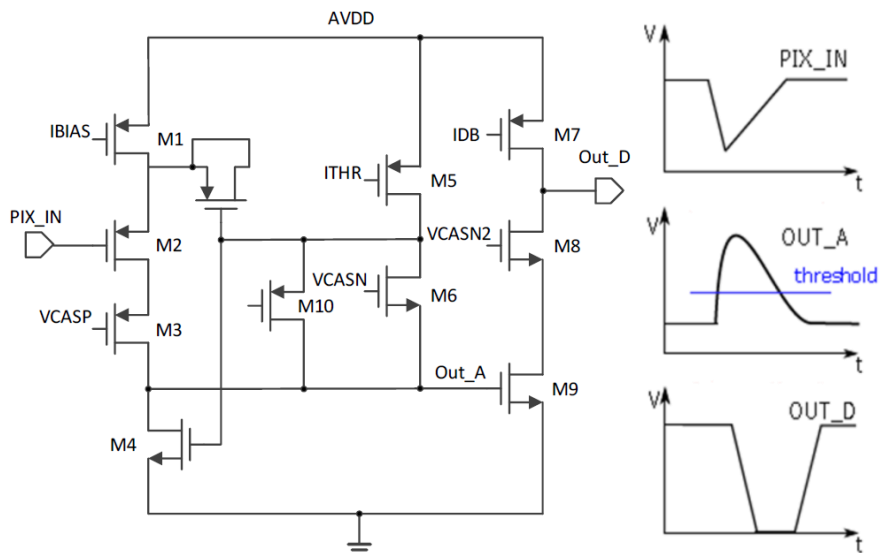




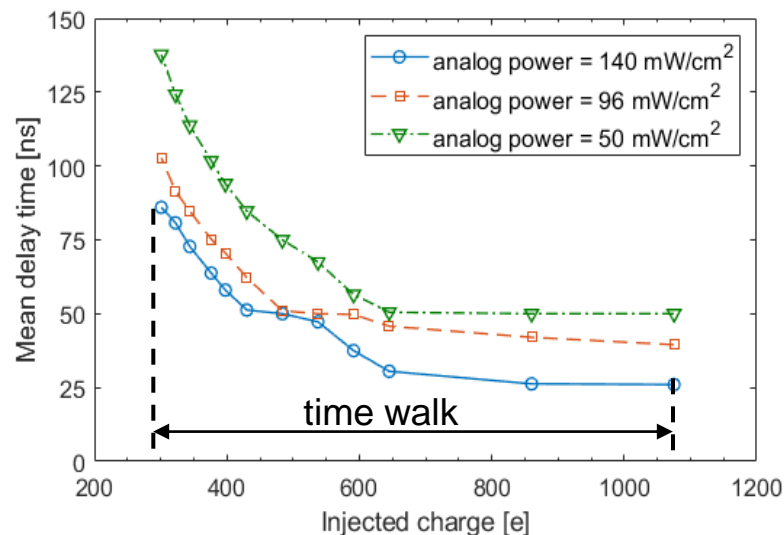
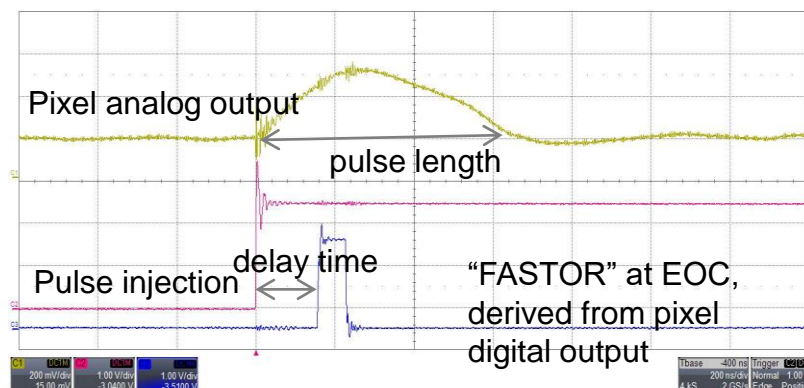
# Pixel analog front-end

## ■ Based on ALPIDE\* front-end scheme

- modified for faster response
- 'FASTOR' signal delivered to the EOC (end of column) when a pixel fired, timestamps of hit recorded at pos. edge of 'FASTOR'



Schematic of pixel front-end



Delay time of FASTOR with respect to the pulse injection vs. injected charge. The delay time was measured by the timestamp of a step of 25 ns.

\*Ref: D. Kim et al. DOI 10.1088/1748-0221/11/02/C02042